

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Masahiko NAKAMORI et al.
App. No	: 10/536,621
Filed	: May 26, 2005
For	: POLISHING PAD AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE
Examiner	: Sylvia R. MacArthur
Art Unit	: 1792
Conf No.	: 9275

RESPONSE**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated December 24, 2008, Applicants respectfully submit the following remarks in connection with the above-captioned application.

Remarks/Arguments begin on page 2 of this paper.